



Enhanced semi-empirical potentials in molecular dynamics simulations of wafer bonding

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Abstract

Molecular dynamics simulations using suitably fitted empirical potentials have been employed to describe atomic interactions at interfaces created by the macroscopic wafer bonding process. Investigating perfect or distorted surfaces (steps, reconstruction, adsorbates, facets, mistilt, twist rotation) of different semiconductor materials as well as of silica enables one to study the elementary processes and the resulting defects at the interfaces as well as to characterize the ability of the potentials used. Preliminary simulations on the basis of empirical potentials developed by the bond order tight-binding approximation, yield enhanced interface structures and energetic relaxations as well as transferability to new materials systems. © 2000 Elsevier Science Ltd. All rights reserved.

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1. Introduction

According to the importance of wafer bonding for semiconductor electronics and micromechanics applications (see the reviews [1,2]) there is an increasing interest to describe the atomic forces at the interfaces. The atomic processes determine the behaviour of extended defects at a microscopic level, thus influencing the macroscopic properties of bonded materials. While, in principle, it is now possible to predict material properties by using quantum-theoretical ab initio calculations with a minimum of free parameters, e.g., density functional (DFT) based approximations, the only method to simulate atomic processes with macro-

scopic relevance is the molecular dynamics (MD) method using suitably fitted many-body empirical potentials. Such simulations enable a large number of particles (10^4 – 10^9) and sufficient relaxation times (10–1000 ps) to be considered. However, the electronic structure and the nature of the covalent bonds can only be described indirectly. Therefore, it is of importance to find physically motivated semiempirical potentials starting mostly with the moments of the electron density and using tight-binding representations [3]. A second moment approximation of the tight-binding model can be used to establish a general form at the level of the Tersoff potential with at least only four free fit parameters [4]. A further enhancement is possible based on the bond order potential (BOP4) [5], which is an approximation up to the fourth-level continued fraction of the Greens function. Its ability is demonstrated in the following for Diamond wafer bonding, the details will be published elsewhere.

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The MD simulations have successfully been used to describe ultra-high-vacuum bonding experiments for Si(100) [6], hydrogen passivated hydrophobic bonding processes [7], and to analyze the defect structure at bonded interfaces [8–10]. However, little has been reported on the bonding of amorphous silica (a-SiO_2) surfaces [11,12], which may be the basis or a first step to describe hydrophilic wafer bonding. In addition, the transferability of the simulations to other materials systems is not well suited up to now. On the other hand, conventional transmission (TEM) and high resolution electron microscopy (HREM) structure imaging has been applied to investigate the resulting interfaces and the defect structures at an atomic level [13], which in combination with calculated IR-spectra provides a good experimental evidence of the results.

2. Method

The method of molecular dynamics (MD) solves Newton's equations of motion for a molecular system, which results in trajectories for all particles considered in the system. Thus, MD provides a tool suitable for simulating time-dependent processes at an atomic level as, e.g., the growth of crystals, the reordering of interfaces, the interaction between adatoms and surfaces as well as the relaxation of core structures of lattice defects. The calculations are performed with the fifth-order predictor–corrector algorithm of Gear using a constant volume (NVE ensemble) or a constant pressure (NpT ensemble) and time steps of the order of 0.25 fs to ensure the proper calculation of surface modes. NVE is preferred for free surfaces and simulations to calculate the diffusion constants, whereas NpT enables the relaxation of the cell dimensions and the application of an outer pressure, which is important for glass generation and the simulation of wafer interfaces, respectively. For controlling the system temperature, either all particle velocities are slightly rescaled at each time step, or solely the outer layers of the structure model, still applying periodic boundary conditions parallel to the interfaces. In the latter case, the energy dissipation and thus the dynamic bonding behaviour are controlled by the transfer rates of the kinetic energy at the borders of the model describing an energy flux into a macroscopic substrate. In addition, for straight defects created at the interfaces the system is coupled elastically to the bulk wafers.

As mentioned above, the interatomic forces in covalent solids can completely be described only if the influence of the local environment according to the quantum electronic structure is also included. Simple pair potentials and potentials of the valence force field or related types as, e.g., the Keating (K) potential, are restricted in their validity to solely small deviations

from the equilibrium. However, empirical potentials have been developed, which allows one to simulate the non-local many-body interaction sufficiently well. The potential most often used for semiconductors is the Stillinger–Weber (SW) potential, consisting of two- and three-body interactions, with a smooth cut-off behind the nearest neighbour distance, and which is fitted to the cohesive energy, the lattice constant, and the melting point. It supports a symmetric quasi-five-fold coordinated reconstruction at interfaces and fails for large distortions in the surrounding of defects. Nevertheless, it allows the next neighbour interaction to be included by rescaling, which is a presupposition to the simulation of the dynamical behaviour without preordered surfaces and prescribed topology. Thus, e.g., the interaction of two silicon surfaces can be studied by correctly revealing the 2×1 reconstruction of a clean Si(100) surface. The potential used for silica is the modified Born–Mayer–Huggins (BMH) ionic pair interaction combined with a weak three-body term. The BMH interaction combines a repulsion and a Coulomb term, which is screened to avoid the long-range Ewald sums, the three-body term is similar to SW. In addition, a Rahman–Stillinger–Lemberg (RSL) term was used for the water interactions.

The potential of Tersoff (here are at least three parametrizations TI, TII, TIII) consists of a third-order cluster structure and has the shape of a bond order, which is a complete other functionality. It predicts the asymmetric reconstruction with fourfold coordinated atoms at interfaces with defects. Therefore, it was applied to investigate the cores of 60° partial dislocations in Si and other defects left after bonding two wafers. Because of the short range of the Tersoff potential it was supposed that the bond topology is given by the usual process starting with separated Si blocks of a suitable surface structure and orientation (surface reconstruction, steps and adsorbates) and applying long-range potentials. For hydrogenated Si-wafer bonding, the Tersoff potential, proposed by Murty and Atwater, was used to model the silicon–hydrogen interaction. The potential is equivalent to TII without hydrogen, and to the potentials used by Brenner for hydrocarbons without silicon. Thus hydrogenated Si(001) surfaces are well described including reconstructions of the (1×1) and (3×1) types.

Most of the existing potentials available are of the SW or T types, compared to each other [14] they offer advantages and disadvantages in range of validity, physical meaning, fitting and accuracy as well as applicability. Such restrictions exist for other potential types, too, even if the embedded atom approximation (EAM) is used or special environment dependencies are constructed to enhance the elastic properties near defects, as, e.g., in [15]. In addition, all potentials are not well applicable for long range interactions. The dif-

ficulty of developing potentials is threefold: one is caused by physical data properties. Tigray [16] develops physical energy is assumed and the promotion of valence s and p orbitals is the expansion of matrix elements of centre integrals in terms. The bond length is determined by Lanczos recursions, the continued fraction expansion and the application of the

3. Results

The molecular dynamics simulation of two perfect and perfectly aligned 2D surfaces by applying a slow heating of the bonded structure from a starting configuration to a final configuration domain of the system. The rotational misorientation of the longer perfectly aligned surfaces is the driving force for atomic steps, to create new defect surfaces, i.e., to increase the neighbour interaction and to create new gained dissipative energies of the system. This implies the bond length, however, after bond formation the interface and defect surfaces of the 60° partial dislocation is accompanied by a rotation of the dimer domains and a change of the intrinsic or extrinsic orientation in the system between, or outside, the rotated by a 90° twist angle as well as other defects as the interface structure, the slow heat transfer in the bulk-like environment, which may have adsorbates has affected surfaces as well as corresponding to the

used to account for the fast dynamics of the hydrogen atoms. External forces in the direction perpendicular to the interface are added to the interaction forces of each slab. The two outermost atomic layers of each slab. The main result of the corresponding MD simulations consists in the finding of an energy barrier characterized by a critical pressure of about 80 MPa to overcome the repulsion forces and to create covalent bonds across the hydrogenated interfaces.

The molecular dynamics simulation starting from perfectly aligned 2×1 reconstructed Si blocks with parallel-oriented surfaces [6]. However, a fast heat transfer, a bounded structure is slow heat transfer approach yields perfectly rotated initial misorientations, result in configurations no longer perfectly coordinate force for the bonding process over facets is the driving force of the energy flux at surfaces, too. The upper terrace behave like per-atomistic steps, i.e., a weak attraction owing to the next neighbor interaction between the dimers to rearrange facets, after bonding over double layer steps, a disturbed interface, after bonding over a row of vacancies. However, the bonding of the lower terrace, too. How- implies the bonding of the higher terrace steps, which may finally relax to a staggered fault of either intrinsic or extrinsic type, depending on the dimer orientation in the adjacent terrace. Thus the interface twist angle as a rotational misorientation under twist-rotational motion. The effect of a small twist angle by a 90° twist-layer steps are charac- terized, or outside, the single-layer steps are charac- terized by a high rate of kinks. The influence of bulk-like environment separated by misfit dislocations, which may have a high rate of kinks. The influence of adsorbates has been investigated, e.g., for hydrogen-ated surfaces assuming two Si(001)- 3×1 blocks [7], where the hydrogen coverage of $4/3$ mono-

3. Results

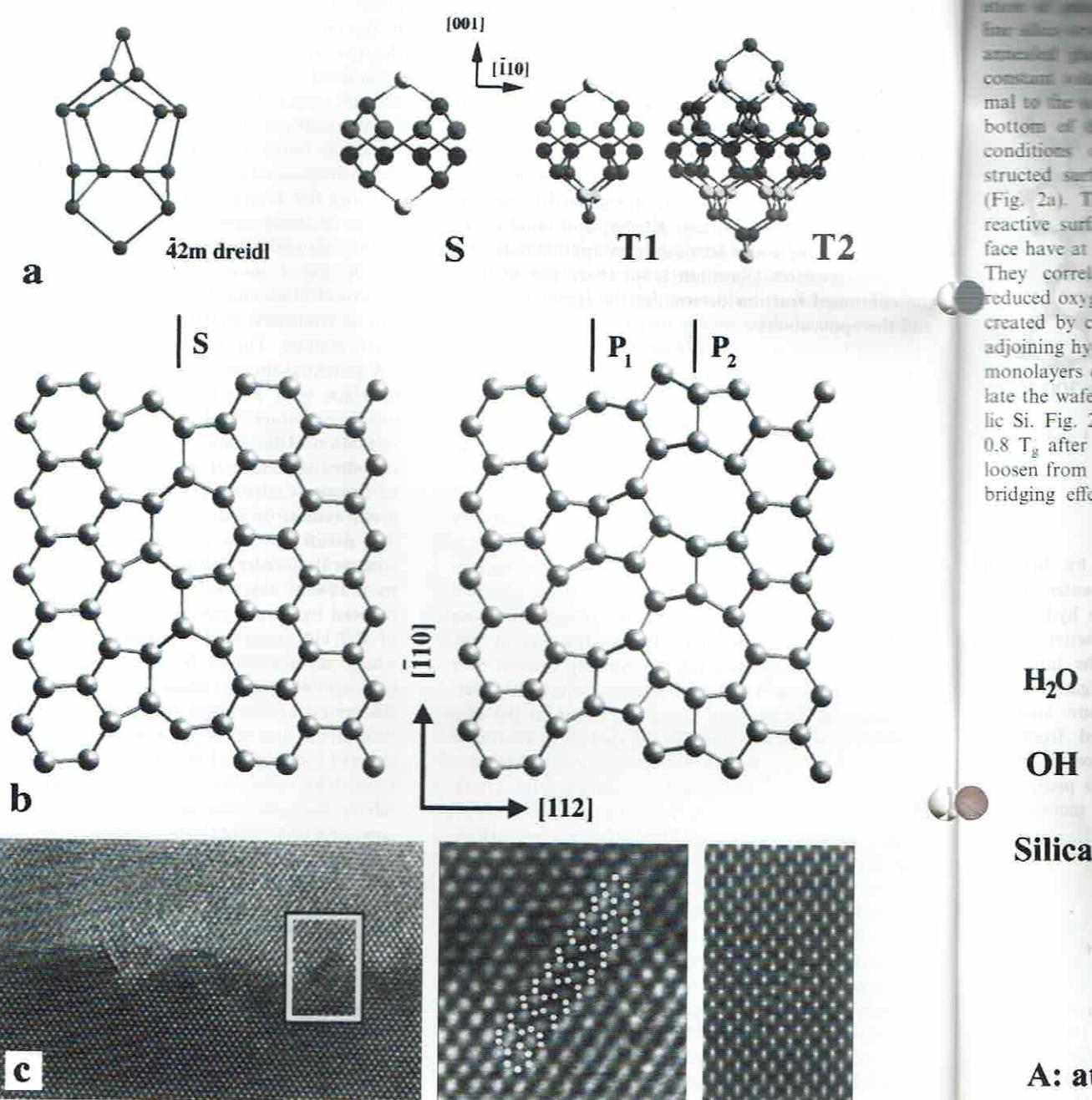


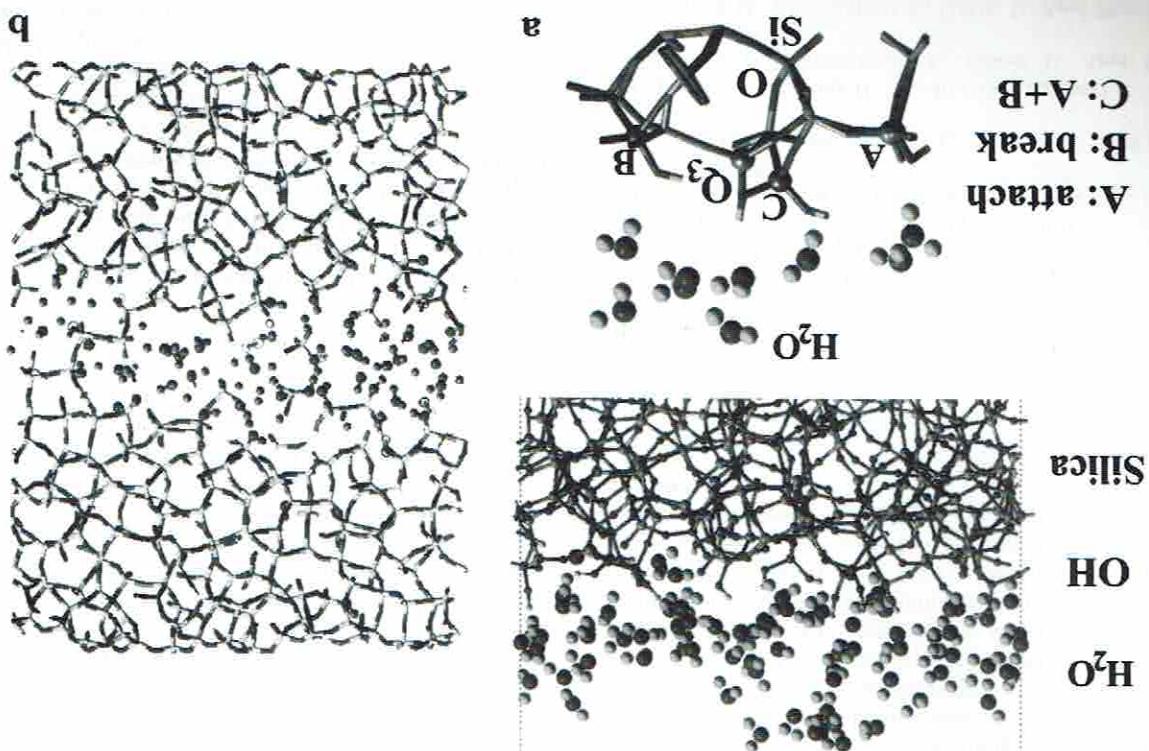
Fig. 1. Defect core reconstructions: (a) $\bar{4}2m$ dreidl as the structural unit of a 90° twist boundary and the core structures of the two stable nodes (T_1, T_2) for fully TII-relaxed screw (S) networks; (b) (111) projections of the perfect $1/2[110]$ screw dislocation (S) and the dissociated 30° partials (P_1, P_2) after 3-step MD relaxation with SW, K, and TII potentials; (c) [110] cross-sectional HREM image of a wafer-bonded twist boundary, enlarged stacking fault ribbon bounded by two 30° partials, and image simulation from the MD relaxed model with (P_1, P_2).

Fig. 2. Snapshots of bond formation at

Figure 2 Snapshots of MD simulated hydrophobic wafer bonding: (a) wafer deposition and silanol reaction sites; (b) covalent silica bond formation at $p = 3$ GPa, $T = 0.8 T_g$, $t = 250$ ps.

the glass transition (T_g) or during long-time simulations. The many open spaces indicate that smaller portions of the surface have broken from this layer and most probably migrated into the gap. This formed an area of the surface through the action of temperature and pressure, helping to form bridging covalent bonds in other sections of the wafer. There are three different regimes, which can be related to experimental observations and the short-time behavior at low temperatures and pressures leads to hydrogen-bonded surfaces with a low bonding energy. The bonding energy can be increased either by increasing the temperature and/or the pressure, or by lengthening the temperature and/or water groups and to lower the dissolution barriers. Thus the interface gap can be closed by forming direct silica-silica bonds. The long-time behavior shows a reactive rearrangement of the surface, which locally leads to strong silica bonds even at low temperatures.

The 2-dimensional simulation of the silica amorphization, hydroxylation and bonding. The generation of amorphous silica models starts from crystalization of amorphous structures. Free surfaces were generated from the silica structures. Free surfaces were generated from amorphized glass models using further relaxation at a constant volume by extending the simulation box normal to the surface, with reflecting walls at the top and bottom of the cell, and applying periodic boundary conditions otherwise. After relaxation, the reconstructed surfaces were bombarded with H_2O groups (Fig. 2a). These relaxed silica glasses have a highly reticular structure. Water molecules settling on the surface have at least three different kinds of bonding sites. They correlate to sites with dangling bond, with reduced oxygen bridging Si—O bonds in the surface, or where silanols are adsorbing hydroxylated surfaces, each covered with 1–2 monolayers of water are brought into contact to simulate the wafer bonding between silica and/or hydrophobic Si. Fig. 2b presents a snapshot of the interface at 0.8 T_g after 250 ps. Longer and shorter silica strands broaden from the surface and migrate into the gap. This bridges the gap from the surface to the interior of the gap. Thus the interface of the wafer bonding between silica and/or hydrophobic Si is formed.



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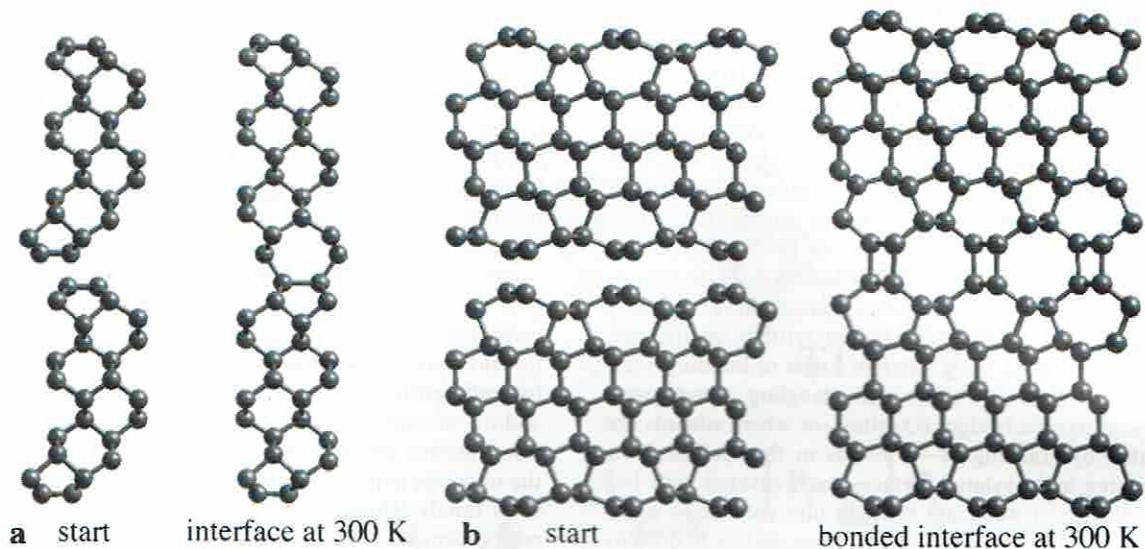


Fig. 3. MD simulations of bonding diamond surfaces: (a) C (001)- 2×1 with tight-binding MD; (b) C (111)- 2×1 and using a BOP4 potential.

equivalent reconstruction in Fig. 3a and b, respectively. Both the tight-binding MD in Fig. 3a and the semi-empirical MD using a BOP4 potential in Fig. 3b, which enables one to use far more atoms in the calculation and which demonstrates the quality of the fit, show the same bonding behaviour. The tight-binding level is necessary to describe correctly the π -bonds. The dimers remain, the π -bonds are broken during the bonding process, there is no graphitization at temperatures not too high. The fourfold coordination is the resulting stable minimum structure. On the (111) surface, therefore, the outermost dimers must be rearranged from threefold coordinations to a fourfold one.

4. Summary

Molecular dynamics simulations based on empirical potentials are used to investigate the elementary steps of bonding two Si(001) wafers. The system is coupled elastically to the bulk wafers, and the energy dissipation is controlled by the transfer rates of the kinetic energy at the borders of the model. Calculated bonding energies and forces strongly depend on the surface termination, native oxides, adsorbates, and the process control. Twisted starting configurations, steps or rotational misorientations result in special interface configurations mostly no longer perfectly coordinated. Bonding energy and forces are determined not only by the surface structure but

also by surface adsorbates as shown by MD of hydrogen on hydrophobic Si and by water–silanol reactions on silica surfaces describing the hydrophilic termination. The simulations lead to a better understanding of the physical processes at the interfaces and support the experimental investigations, especially the electron microscope structure analysis. Simulations based on potentials derived from the bond order expansion are used to enhance the physical reliability of the investigations and to predict the bonding behaviour of a wide variety of semiconductor surfaces.

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of semiconductors to predict the physics involved from the structure analysis, especially water-silanol interactions, a better understanding of wafer bonding.

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